



photolithography interferometer mirror stage alignment mark

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Jovian Planet Finder optical system

JE Krist, M Clampin, L Petro, RA Woodruff, HC Ford ... - Proceedings of SPIE, 2003 - www-int.stsci.edu
... by ASML (formerly Tinsley) for UV **photolithography**. ... map of the corrector **mirror**
fabricated by ... a proprietary differential phase **interferometer**; (Right) Sum of ...
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Magnet arrays for synchronous machines

DL Trumper, ME Williams, TH Nguyen - Conference Record, 28th IEEE Industry Applications Society ..., 1993 - [ieeexplore.ieee.org](#)
... a magnetic bearing **stage** for precision motion control in **photolithography** [3—5 ... feedback
in this axis is via a plane **mirror laser interferometer**, and the ...
Cited by 11 - [Web Search](#) - [ieeexplore.ieee.org](#)

Wafer Alignment for Canon Stepper Dr. Lynn Fuller

M Professor - [rit.edu](#)
... The **stage** accuracy is monitored periodically to ensure that the **interferometer** is
working ... **mirror** ... overlay are the result of the most recent **photolithography**. ...
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Manufacturing with DUV lithography

SJ Holmes, PH Mitchell, MC Haakey - IBM Journal of Research and Development, 1997 - [research.ibm.com](#)
... Evolution of DUV **photolithography** tool. ... optics required a specially developed DUV
interferometer to reach ... on a fly's-eye lens and a vibrating **mirror** to achieve ...
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P-40: 0.5μ m Enabling Lithography for Low-Temperature Polysilicon Displays

F Clube, M Jorda, S Mourgue, AR Nobari, S Inoue, C ... - [holtronic.ch](#)
... the orthogonality error of the **interferometer** mirrors ... Unlike lens- and **mirror**-based
imaging systems, TIR ... Large-field, high-resolution **photolithography**", SPIE Vol ...
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Improvements in index alignment method for laser-fiber array packaging

MS Cohen, MJ DeFranza, FJ Canora, MF Cina, R Rand, ... - IEEE Transactions on Components, Packaging, and ..., 1994 - [ieeexplore.ieee.org](#)
... as in contact **photolithography**. During ... system. The new system incorporated
laser-interferometer feedback in the **stage** Page 2 Fig. 1 ...
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Large-field scanning laser ablation system

FE Doany, T Ainsworth, N Bobroff, D Goodman, AE ... - IBM Journal of Research and Development, 1997 - [research.ibm.com](#)
... tool very similar to a **photolithography** stepper ... a Hewlett-Packard 5501 plane **mirror**
interferometer using an ... This lens design and folding **mirror** arrangement also ...
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Large-field

T Ainsworth, N Bobroff - [research.ibm.com](#)
... ablation tool very similar to a **photolithography** stepper. ... A plane **mirror interferometer**
is used to precisely determine and control the **stage** position ...
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lithography interferometer mirror stage alignment mark

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Scanning Beam Interference Lithography

PT Konkola, CG Chen, RK Heilmann, GS Pati, ML ... - Proceedings of the Sixteenth Annual Meeting of the American ... , 2001 - snl.mit.edu

 ... Column **mirror** Left beam ... Substrate and Metrology Frame 3.01E-09 Displacement

Interferometer 3.45E-09 **Lithography Interferometer** Phase 2.25E-09 rss error ...

 Cited by 3 - [View as HTML](#) - [Web Search](#) - [snl.mit.edu](#)

Nanometer-accurate grating fabrication with scanning beam interference lithography

CG Chen, PT Konkola, RK Heilmann, C Joo, ML ... - Nano-and Microtechnology: Materials, Processes, Packaging, ... - snl.mit.edu

 ... two arms of the **lithography interferometer**, the requirement ... to the x-axis **stage**
interferometer mirror (Fig. ... The **alignment** ensures the fringe perpendicularity to ...

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Dimensional metrology for nanometre-scale science and engineering: towards sub-nanometre accurate ...

RK Heilmann, CG Chen, PT Konkola, ML Schattenburg - Nanotechnology, 2004 - iop.org

 ... Errors in the UV **lithography interferometer** are due to ... index variations, periodic

 UV **interferometer** errors, and ... optics relative to the column reference **mirror**. ...

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Jovian Planet Finder optical system

JE Krist, M Clampin, L Petro, RA Woodruff, HC Ford ... - Proceedings of SPIE, 2003 - www.int.stsci.edu

 ... in polishing optics for extreme-ultraviolet **lithography** have shown ... Using an

interferometer on the ground, a young ... A small, microfigured **mirror** mounted on an ...

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Manufacturing with DUV lithography

SJ Holmes, PH Mitchell, MC Hakey - IBM Journal of Research and Development, 1997 - research.ibm.com

 ... Elmer, Perkin-Elmer/ SVG **Lithography**, Nikon, SVG **Lithography**. ... required a specially

 developed DUV **interferometer** to reach ... eye lens and a vibrating **mirror** to achieve ...

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P-40: 0.5µ m Enabling Lithography for Low-Temperature Polysilicon Displays

F Clube, M Jorda, S Mourgue, AR Nobari, S Inoue, C ... - holtronic.ch

 ... the orthogonality error of the **interferometer** mirrors ... Unlike lens- and **mirror**-based

 imaging systems, TIR ... a display substrate using TIR holographic **lithography**. ...

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Dimensional Metrology for Nanometer-Scale Science and Engineering

RK Heilmann, CG Chen, PT Konkola, ML Schattenburg - snl.mit.edu

 ... optic modulators in each **lithography** arm, thereby ... as those due to **stage mirror**

 non-flatness ... expansion effects, and periodic **stage interferometer** non-linearities ...

[Web Search](#)

... -Precision Multilayer Coating of the First Set of Optics for an Extreme-Ultraviolet Lithography ...

C Montcalm, RF Grabner, RM Hudyma, MA Schmidt, E ... - Applied Optics, 2002 - ao.osa.org

 ... coating specifications are driven by **lithography** metrics such ... provide an extra spare

mirror for 11.850 ... with a phase-shifting point- diffraction **interferometer**. ...

[Web Search](#) - [aoot.osa.org](#) - [adsabs.harvard.edu](#) - [ncbi.nlm.nih.gov](#) - [all 6 versions](#) »